

L4: (0) 2 and (substrate a
 L6: (0) 2 and (substrate a
 L7: (25) 2 and (electromag
 L5: (21) 2 and (substrate
 L8: (862) 2 and 'MEMS'
 L9: (477) 8 and (actuator
 Failed
 Saved

DBs: USPAT,EPO,JPO Plurals
 Highlight all hit terms initial
 Default operator: OR
 8 and (actuator and substrate)

	<input type="checkbox"/>	<input checked="" type="checkbox"/>	Document ID	Issue Date	Pages	Title	Current OR	Current XRef
1	<input type="checkbox"/>	<input type="checkbox"/>	US 6563238 B1	20030513	14	Comb structure using magnetic force and actuator	310/15	
2	<input type="checkbox"/>	<input type="checkbox"/>	US 6563184 B1	20030513	21	Single crystal tunneling sensor or switch with	257/419	257/254;
3	<input type="checkbox"/>	<input type="checkbox"/>	US 6563133 B1	20030513	24	Method of epitaxial-like wafer bonding at low	257/52	257/415;
4	<input type="checkbox"/>	<input type="checkbox"/>	US 6563106 B1	20030513	23	Micro-electro-mechanical-system (MEMS) mirror device and	250/216	250/208.1;
5	<input type="checkbox"/>	<input type="checkbox"/>	US 6562523 B1	20030513	56	Direct write all-glass photomask blanks	430/5	430/13;
6	<input type="checkbox"/>	<input type="checkbox"/>	US 6562000 B2	20030513	18	Single-use therapeutic substance delivery device	604/48	604/132;
7	<input type="checkbox"/>	<input type="checkbox"/>	US 6561725 B1	20030513	19	System and method for coupling microcomponents	403/326	604/67
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6561627 B2	20030513	12	Thermal actuator	347/54	24/453;
9	<input type="checkbox"/>	<input type="checkbox"/>	US 6561224 B1	20030513	13	Microfluidic valve and system therefor	137/831	24/625;
10	<input type="checkbox"/>	<input type="checkbox"/>	US 6560384 B1	20030506	8	Optical switch having mirrors arranged to	385/18	137/827;
11	<input type="checkbox"/>	<input type="checkbox"/>	US 6559550 B2	20030506	12	Nanoscale piezoelectric generation system using	290/1R	251/129.06;